

Docket No. 205890US99



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JPW 2811  
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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

IN RE APPLICATION OF: Jamal RAMDANI, et al.

SERIAL NO: 09/721,566

GAU: 2811

FILED: November 22, 2000

EXAMINER: HU, SHOUXIANG

FOR: STRUCTURE AND METHOD FOR FABRICATING SEMICONDUCTOR STRUCTURES AND DEVICES UTILIZING THE FORMATION OF A COMPLIANT SUBSTRATE FOR MATERIALS USED TO FORM THE SAME

**EXPRESS ABANDONMENT UNDER 37 CFR 1.138**

COMMISSIONER FOR PATENTS  
ALEXANDRIA, VIRGINIA 22313

SIR:

Applicant(s) wish to disclose the following information.

☒ **Express Abandonment**

Applicant's Representative requests that the above-identified application be expressly abandoned as of the filing date of this paper.

☐ **Express Abandonment in Favor of a Continuing Application**

Applicant's Representative requests that the above-identified application be expressly abandoned as of the filing date accorded the continuing application filed herewith.

☐ **Petition for Express Abandonment to Avoid Publication under 37 C.F.R. 1.138(c)**

Applicant's Representative hereby petitions to expressly abandon the above-identified application under 37 CFR 1.138(c) to avoid publication.

The required petition fee under 37 CFR 1.17(h) of \$130.00 is enclosed herewith by credit card payment form and any further charges may be made against the Attorney of Record's Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

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Respectfully submitted,

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